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00862.022246

PATENT APPLICATION

APR 30 2003

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Kazunori IWAMOTO et al.

Application No.: 09/866,600

Filed: May 30, 2001

For: STAGE APPARATUS WHICH SUPPORTS INTERFEROMETER,
STAGE POSITION MEASUREMENT METHOD, PROJECTION
EXPOSURE APPARATUS, PROJECTION EXPOSURE
MAINTENANCE METHOD, SEMICONDUCTOR DEVICE
MANUFACTURING METHOD, AND SEMICONDUCTOR
MANUFACTURING FACTORY

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: Examiner: H. Nguyen
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: Group Art Unit: 2851
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:
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April 30, 2003

Commissioner for Patents
Washington, D.C. 20231

Sir:

Transmitted herewith is an Amendment in the above-identified application.

☒ No additional fee is required.

The fee has been calculated as shown below:

CLAIMS AS AMENDED						
	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NO. PREVIOUSLY PAID FOR	PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL CLAIMS	30	MINUS	30	= 0	x \$9 \$18	\$0.00
INDEP. CLAIMS	5	MINUS	5	= 0	x \$42 \$84	\$0.00
Fee for Multiple Dependent claims \$140/\$280						—
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT						\$0.00

- ☐ °Verified Statement claiming small entity status is enclosed, if not filed previously.
- ☐ A check in the amount of \$_____ is enclosed including the additional claims fees.
- ☐ Charge \$____ to Deposit Account No. 06-1205. A duplicate of this sheet is enclosed.
- ☒ Any prior general authorization to charge an issue fee under 37 CFR 1.18 to Deposit Account No. 06-1205 is hereby revoked. The Commissioner is hereby authorized to charge any additional fees under 37 CFR 1.16 and 1.17 which may be required during the entire pendency of this application, or to credit any overpayment, to Deposit Account No. 06-1205. A duplicate of this paper is enclosed.
- ☐ A check in the amount of \$_____ to cover the fee for a two month extension is enclosed.
- ☐ A check in the amount of \$_____ to cover the Information Disclosure Statement fee is enclosed.
- ☒ Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should be directed to our address given below.

Respectfully submitted,



Attorney for Applicants
Steven E. Warner
Registration No. 33,326

FITZPATRICK, CELLA, HARPER & SCINTO

30 Rockefeller Plaza

New York, New York 10112-3801

Facsimile: (212) 218-2200

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K. Duncan
5/6/03

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EXPOSURE APPARATUS MAINTENANCE
METHOD, SEMICONDUCTOR DEVICE
MANUFACTURING METHOD, AND
SEMICONDUCTOR MANUFACTURING FACTORY :

)
: Examiner: H. Nguyen

)
: Group Art Unit: 2851

)
:
: April 30, 2003

Commissioner for Patents
Washington, D.C. 20231

REQUEST FOR APPROVAL OF DRAWING CHANGES

Sir:

Applicants request that the Examiner approve the changes to Figures 5 and 6, as shown in red on the attached sketches, enclosed in duplicate.

In Figure 5, under "FIG. 5," insert -- PRIOR ART --, as shown.


In Figure 6, under "FIG. 6," insert -- PRIOR ART --, as shown.

Favorable consideration is requested.

Approved
for
initial
7/6/03
HN

Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.

Respectfully submitted,

A handwritten signature in dark ink, appearing to read "Steven E. Warner", is written over a horizontal line.

Attorney for Applicants

Steven E. Warner

Registration No. 33,326

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